



Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 128865		APPLICATION NO. 10/587,268	
				APPLICANTS Hiroaki TAKAIWA et al.			
				FILING DATE July 26, 2006		GROUP 2882	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)							
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